



35.C15518

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PATENT APPLICATION

TC 2800 MAIL ROOM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TOHRU DEN ET AL.

Application No.: 09/895,464

Filed: July 2, 2001

For: METHOD OF MANUFACTURING)  
STRUCTURE WITH PORES AND :  
STRUCTURE WITH PORES )

Examiner: Not Yet Assigned

Group Art Unit: 2811

October 9, 2001

Commissioner for Patents  
Washington, D.C. 20231

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TC 2800 MAIL ROOM

PRELIMINARY AMENDMENT

Sir:

Prior to examining the subject application on the merits, please amend this application as follows and consider the following remarks.

IN THE SPECIFICATION:

Please replace the paragraph beginning at page 4, line 13 and ending at page 4, line 17 with the following paragraph. A marked-up copy of the original paragraph showing the changes thereto is attached.

A1

--Another report by Masuda intends to dispose pores in rows by anodically oxidizing an Al film in a film surface direction, the Al film being sandwiched between insulators (refer to "Appl. Phys. Lett." 63, p. 3155 (1993)).--